CLAIMS

[Claim 1] A polishing head for polishing a substrate, comprising:

a pressing member configured to press a polishing tape against the substrate; and

a tape hook configured to restrict movement of an edge of the polishing tape in a direction toward the substrate, the tape hook having a tape positioning surface that faces a polishing surface of the edge of the polishing tape,

the tape hook has a protrusion that protrudes toward the pressing member,

the protrusion is located between the substrate and the edge of the polishing tape when the pressing member presses the polishing tape against the substrate.

[Claim 2] The polishing head according to claim 1, wherein the tape hook is disposed adjacent to the pressing member.

[Claim 3] A polishing head for polishing a substrate, comprising:

a pressing mechanism configured to press a polishing tape against the substrate; and

a tape hook configured to restrict movement of an edge of the polishing tape in a direction toward the substrate, the tape hook having a tape positioning surface that faces a polishing surface of the edge of the polishing tape,

wherein the tape hook comprises a plurality of tape hooks arranged at both sides of the pressing mechanism.

[Claim 4] The polishing head according to claim 3, wherein the plurality of tape hooks have a plurality of tape positioning surfaces that face polishing surfaces of both edges of the polishing tape.

[Claim 5] A polishing head for polishing a substrate, comprising:

a pressing member configured to press a polishing tape against the substrate;

a tape hook configured to restrict movement of an edge of the polishing tape in a

direction toward the substrate; and

a pressing-member holder that holds the pressing member,

wherein the tape hook has a tape positioning surface that faces a polishing surface of the edge of the polishing tape, and

a distance from a reference plane in the pressing-member holder to an end surface of the tape hook is shorter than a distance from the reference plane to a tape pressing surface of the pressing member.

[Claim 6] The polishing head according to claim 5, wherein the tape hook has a protrusion that protrudes toward the pressing member, one side of the protrusion forming the tape positioning surface and an opposite side of the protrusion forming the end surface of the tape hook.

[Claim 7] The polishing head according to claim 6, wherein the protrusion is located between the substrate and the edge of the polishing tape.

[Claim 8] The polishing head according to any one of claims 1 to 7, wherein the tape hook and the pressing mechanism are movable together.

[Claim 9] A polishing apparatus comprising:

a substrate holder configured to hold a substrate; and

a polishing head according to any one of claims 1 to 7 configured to polish the substrate.